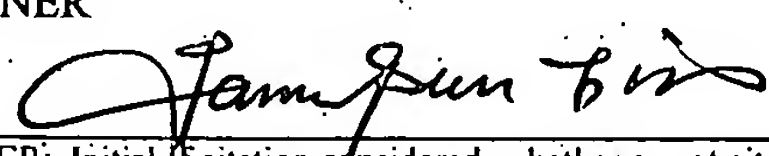


PTO-1449		Application No. Unknown 10/615,048		Applicant(s) James W. Blatchford, Jr., et al.			
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U.S. PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A						
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	R						
EXAMINER 				DATE CONSIDERED 11-03-04			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							

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